

Influence of Defects on the Splitting of the Acceptor Ground State in Silicon

A. Ambrosy and K. Laßmann

Physikalisches Institut der Universität Stuttgart, Pfaffenwaldring 57
D-7000 Stuttgart 80, Fed. Rep. of Germany

A.M. de Goër and B. Salce

Centre d'Etudes Nucléaires de Grenoble, F-38000 Grenoble, France

H. Zeile

Valvo Röhren-und Halbleiterwerke der Philips GmbH, Stresemannallee 101
D-2000 Hamburg 54, Fed. Rep. of Germany

The distribution of strain fields from specified defects in otherwise pure silicon crystals is reflected in the resulting distribution of splittings E of the partially orbitally degenerate Γ_0 ground state of effective mass acceptors. The spectral density $N(E)$ can be probed by resonant scattering of $h\nu = E$ ultrasonic [1] or $3.8 \text{ kT} \approx E$ thermal phonons [2]. The results of both methods (in the following: $\alpha(\nu)$ and $\kappa(T)$) are compared for Si(B) and Si(In) crystals containing definite amounts of C and O [Tab.1]. Monte Carlo calculations (M.C.) for point defects and for 60° dislocations in Si (isotropic approximation) have been made to obtain $N(E)$ as well as $D_1(E)$, the latter being the mean coupling constant of a specified phonon ($L, T_1, T_2, [100], [110], [111]$) to splittings at E . This average coupling for all 9 types of phonons practically does not depend on E and therefore presumably also for the thermal phonons. Thus, though in both experiments $D_1^2(E) \cdot N(E)$ is measured the form of $N(E)$ is preserved and D_1 can be estimated by integrating over the whole distribution normalizing with $n_a = \int N(E) dE$. The calculated distribution for point defects derives from Lorentzians and from Gaussians for dislocations. Fig.1 shows $D_1^2 \cdot N(E)/n_a$ for Si(B) crystals with various concentrations of point defects from $\alpha(\nu)$. Analysis shows that only for the crystal with the highest concentration of point defects (S 80) $D_1^2 \cdot N(E)/n_a$ can be fitted by the calculated "Lorentzian". The smaller the concentration the more "Gaussian" is mixed into $N(E)$ merging into the quasi Gaussian residual distribution of unknown origin of the pure crystal S 87. S125 and S 54 of Fig.2

Fig. 1

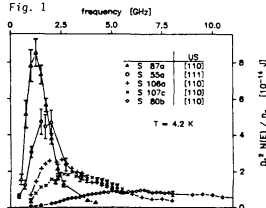


Fig.1. Splitting distribution of Si(B) with point defects

Fig. 2

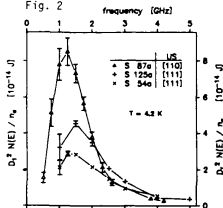


Fig.2. Splitting distribution of pure Si for different concentration of boron

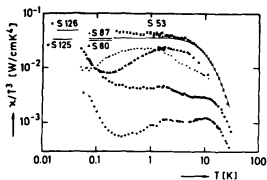


Fig.3. Thermal scattering in Si(B)

are pure crystals with high [B], where a dynamic B-B interaction had been found by hole burning [3]. Possibly an interaction shows up also in these curves, not so much in the form of $N(E)$ but in a reduction of D_1 . Analogous results in the form $\kappa(T)/T^3$ vs. T are shown for crystals with as sawn side faces in Fig.3. The extra scattering below 1K is due to the split levels, whereas the depression around 5K - going monotonously with [B] - is interpreted as due to Jahn-Teller resonance scattering [4]. Boundary scattering for the defect-free and undoped S 53c is found to be temperature dependent and about 20 % larger than the theoretical Casimir term. A check with chemically polished side faces and also with an extra dummy collar showed that there is only negligible change for the S 80 but that thermometer mounting and strains from side face damage may have a significant influence for S 87 with narrow distribution. For the S 53 with polished side faces $\kappa(T)/T^3$ increases by about 1.6 at 2 K to 3.4 at 60 mK. These facts make it difficult to analyse narrow distributions of small acceptor concentrations where the extra scattering is at low temperatures and weak. In crystals with high [B] (S 125, S 126) the scattering regime is much larger than expected from $\alpha(v)$. Again the S 80 can be fitted by the calculated distribution but with a maximum at 8.3 GHz instead of about 6.5 GHz as obtained from $\alpha(v)$. The experimental/theoretical average coupling constants are 1.22/1.2 eV and 1.94/2.22 eV for $\kappa(T)$ and $\alpha(v)$ respectively.

Table 1: Si(B) samples

sample	$\rho(\Omega\text{cm})$	concentrations [10^{21}m^{-3}]			ν_{max} in GHz from	
		[B]	[O]	[C]	$\alpha(v)$	$\kappa(T)$
S 53*	>2500.0	0.005	< 0.5	—	1.2	
S 54*	0.3	85.0			1.2	
S 55	1.6	9.0	< 2.0	75.0	1.7	
S 80	10.85	1.2	570.0	41.0	6.5	8.3
S 87*	2.5	5.4	< 2.0	< 5.0	1.2	4.6
S 108		5.0	<20.0	200.0	2.2	
S 107		1.8	<20.0	280.0	2.8	
S 125*	0.74	24.0			1.2	
S 126	0.3	85.0	200.0	<50.0		10.4

* Wacker chemitronic, waco quality

For Si(In) the deformation potential constants being about 0.6 of those of Si(B), one would expect the distributions and the phonon scattering to be correspondingly smaller. A possible In-In interaction should set in at a concentration about 8 times larger than for B be-

cause of the smaller Bohr radius. In Tab. 2 reliable figures for the concentration can be given only for samples S 52 and S 123 where temperature-dependent Hall measurements have been made [5]. The results of $\kappa(T)$ are normalized to the pure case to show the additional scattering [Fig.4]. The Jahn-Teller resonance at about 20 K increases monotonously with $[In]$ whereas the scattering at low temperatures is due to the splitting distributions. For S 123 from $\alpha(\nu)$ we get $E_{\max} = 3.2$ GHz as compared to ~ 5 GHz from $\kappa(T)$. Estimating the elastic strength A from the covalent radii gives $A_{In}/A_C = 0.68$ and taking into account the deformation potential constants one would obtain $E_{\max} = 0.5$ GHz from M.C. For the S 52 with high concentration of point defects a fit somewhat broader than "Lorentzian" gives $E_{\max} = 14.5$ GHz, whereas from M.C. one would expect $E_{\max} < 9$ GHz if the indicated figures for $[In]$ and $[O]$ are correct. The deformation potential constant from this analysis is 0.24 eV as compared to the theoretical value 0.72 eV. Since $[In]$ is rather high the reduction could be due to an In-In interaction in analogy to the case of boron.

Table 2: Si(In) samples

sample	$\rho(\Omega cm)$	concentrations [$10^{21} m^{-3}$]			ν_{max} in GHz from $\alpha(\nu)$	ν_{max} in GHz from $\kappa(T)$
		$[In]$	$[O]$	$[C]$		
S 33	2.0		700.0			
S 52	0.1	500.0	800.0			14.5
S 123	1.29	100.0	<10.0	< 1.0	3.2	≈ 5
S 196	0.55					

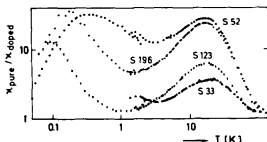


Fig.4. Thermal scattering in Si(In)

- 1 H. Zeile, K. Laßmann, Phys. Stat. Sol. (b) 111, 555(82)
- 2 A. M. de Goer, M. Locatelli and K. Laßmann, J. de phys. 42 C 6-235(81)
- 3 H. Zeile, U. Harten and K. Laßmann, Phys. Stat. Sol. (b) 111, 213(82)
- 4 J. Maier and E. Sigmund, these Proceedings
- 5 S 52 obtained by J. S. Blakemore (sample 260 in PR B4 1873(71))
S 123 obtained by R. Helbig, Univ. Erlangen (sample Ru 237/1-1b)